

Submitting MMC Technical Reports on Terminology to the IEC

While the Micromachine Center was carrying out R&D on Micromachine Technology under METI's Industrial Science and Technology Frontier Program over a ten-year period, it also stressed the standardization of terminology and measurement evaluation, even at the research stage. Accordingly, the Center organized working groups for measurement evaluation and terminology under the Committee on Micromachine Standardization (chairman: Hisayoshi Sato, Professor of Chuo University) and conducted studies on these topics. The results were compiled in technical reports that have been published. For terminology, definitions were confirmed in English and Japanese for 220 terms. The Micromachine Center led discussions on this glossary at an online International Standardization Forum, while publishing the glossary on its home page and collecting comments regarding its contents.

After it was determined that nearly all opinions had been collected, the Center received approval from the WG for terminology to submit the glossary formally to the IEC. The Center also formally submitted the glossary to the IEC/TC47/WG4 after receiving approval from a domestic committee (JEITA) on TC47 (semiconductor devices).

The copy below shows a letter from the IEC notifying all countries on July 5 of Japan's proposal regarding terminology and definitions. As shown by the notifications, P- members are urged to vote by

October 4 on whether or not to adopt this proposal. If the proposal is adopted at this time, then the issue will be offered up for a discussion on international standards. However, the proposal has many hurdles to overcome before it can finally be standardized.

Through these achievements, however, the standardization activities of the Center have entered an international phase, thereby achieving one milestone. In keeping with this, tensile testing methods for thin films conducted under commission of NEDO have entered a stage this fiscal year in which a standardization proposal will be created with the support of the Japanese Standards Association.

The following is the list of the committee members (at the time of the committee activities) who contributed to developing the terminology.

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| Chairman | Nobuyuki Moronuki (Tokyo Metropolitan University Graduate School) |
| Members | Nobuyuki Kabei (Saitama Cardiovascular and Respiratory Center)
Masaaki Ikeda (OMRON CORP.)
Koichi Suzumori (TOSHIBA CORP.)
Hiromu Narumiya (MITSUBISHI ELECTRIC CORP.)
Takefumi Kabashima (YASKAWA ELECTRIC CORPORATION) |

	47/1644/NP NEW WORK ITEM PROPOSAL														
<p>Classification according to IEC Directives Supplement, Table 1 A3</p> <p>A proposal for a new work item within the scope of an existing technical committee or subcommittee shall be submitted to the Central Office. The proposal will be distributed to the P-members of the technical committee or subcommittee for voting, and to the O-members for information. The proposer may be a National Committee of the IEC, the secretariat itself, another technical committee or subcommittee, an organization in liaison, the Standardization Management Board or one of the advisory committees, or the General Secretary. Guidelines for proposing and justifying a new work item are given in ISO/IEC Directives, Part 1, Annex C (see extract overleaf). This form is not to be used for amendments or revisions to existing publications.</p> <p>The proposal (to be completed by the proposer)</p>	<table border="1" style="width: 100%; border-collapse: collapse;"> <tr> <td style="width: 50%;">Proposer <u>Japan</u></td> <td style="width: 50%;">Date of proposal 2002-07</td> </tr> <tr> <td>TC/SC 47</td> <td>Secretariat Korea</td> </tr> <tr> <td>Date of circulation 2002-07-05</td> <td>Closing date for voting 2002-10-04</td> </tr> </table>	Proposer <u>Japan</u>	Date of proposal 2002-07	TC/SC 47	Secretariat Korea	Date of circulation 2002-07-05	Closing date for voting 2002-10-04								
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